

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Shunpei Yamazaki et al.	Art Unit :	2673
Serial No. :	09/504,235	Examiner :	David L. Lewis
Filed :	February 15, 2000	Conf. No. :	7610
Title :	METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE		

MAIL STOP RCE

Commissioner for Patents
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INFORMATION DISCLOSURE STATEMENT

Applicants request consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request.

This filing is being made with the filing of a Request for Continued Examination. No fee is required.

Respectfully submitted,

Date: August 15, 2006



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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977-008004	Application No. 09/504,235
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Shunpei Yamazaki et al.	
		Filing Date February 15, 2000	Group Art Unit 2673

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	AL	JP06-504139	12 MAY 1994	JAPAN			Abstract	
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AQ	Sumiyoshi et al., "DEVICE LAYER TRANSFERRED POLY-Si TFT ARRAY FOR HIGH RESOLUTION LIQUID CRYSTAL PROJECTOR", International Electron Devices Meeting, December 3-6, 1989, IEDM 89, pp. 165-168.
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	